

Development of a Thermal Infrared Image Sensor (based on Microbolometers)

EPICTURE THIS WORKSHOP 2023

<https://project-mantis.eu/#epicture>

Wd 21 June 2023, 13:00 - 21:00

Delft University of Technology, Netherlands



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All slides are non-confidential and can be
made available publicly.



Thermal Infrared Imaging



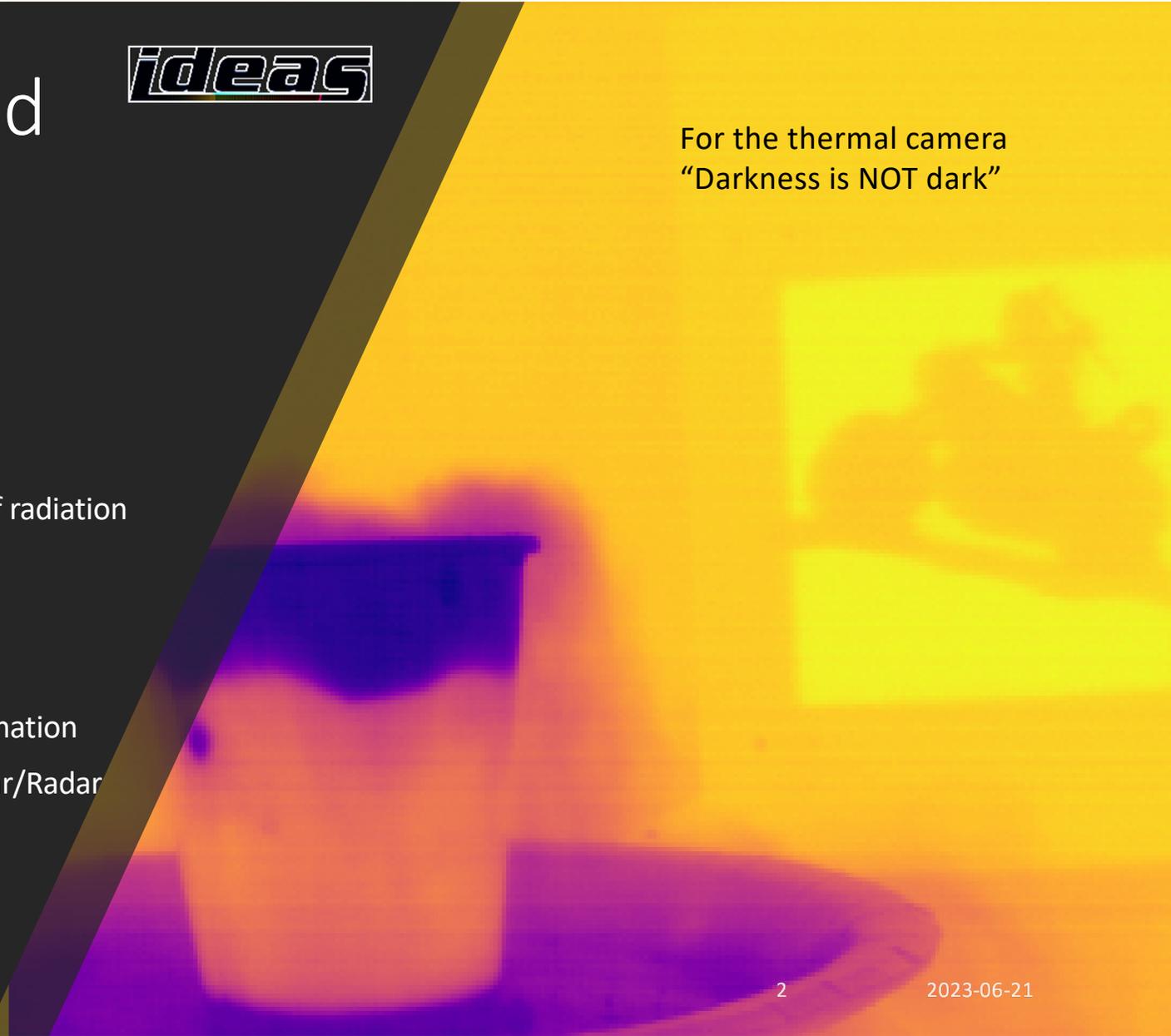
Thermography
– images/video from radiated heat

Radiometry
– Surface temperature from intensity of radiation

Benefits of Thermal Infrared Imaging

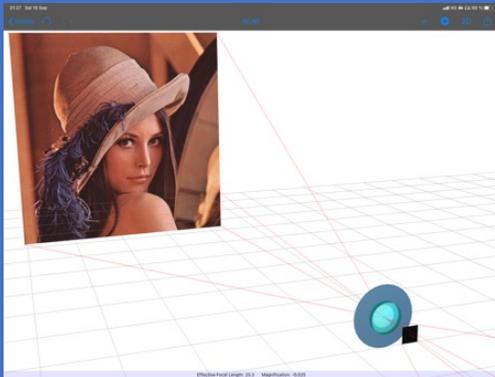
- See through smoke, vapor, fog, dust
- Day and night vision – without illumination
- Passive imaging method – unlike Lidar/Radar

For the thermal camera
“Darkness is NOT dark”

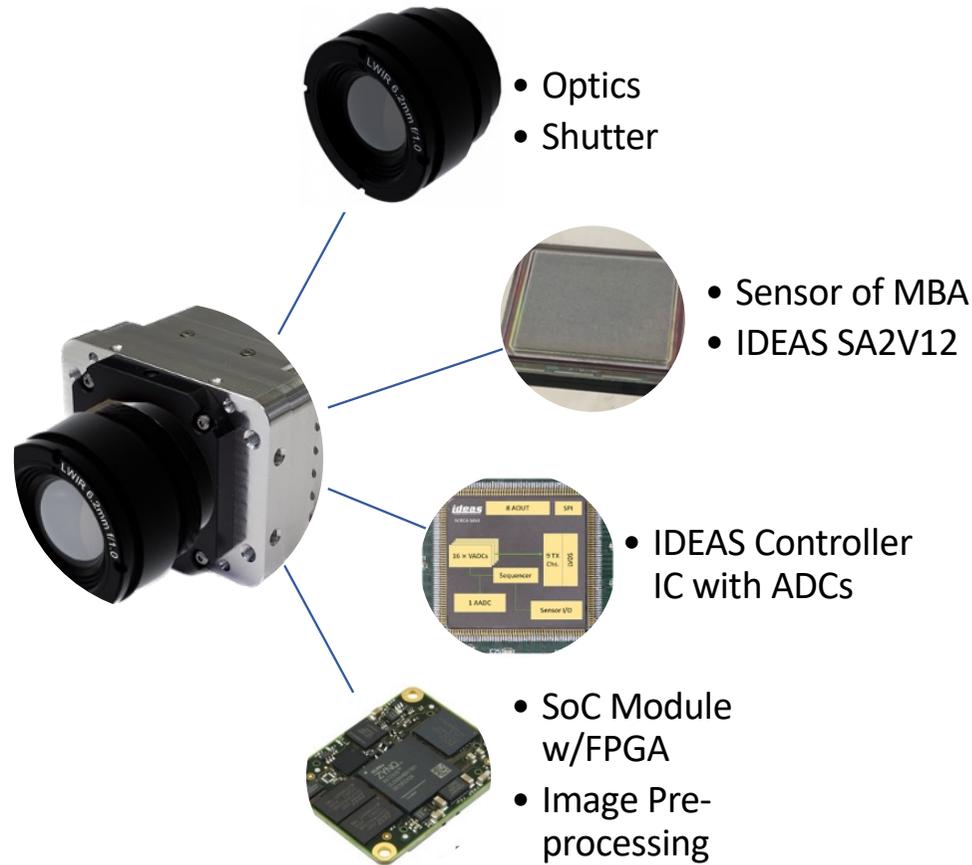


Components in Our Thermal Infrared Camera

Real world object...



... emits thermal radiation which casts an image in the sensor



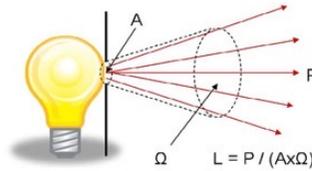
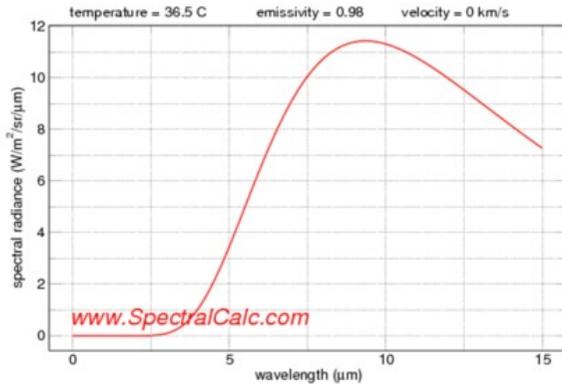
Video images...



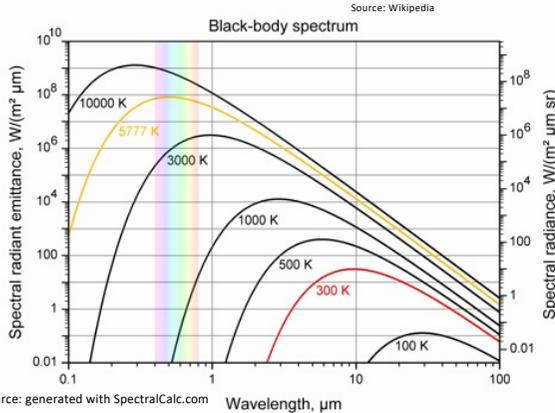
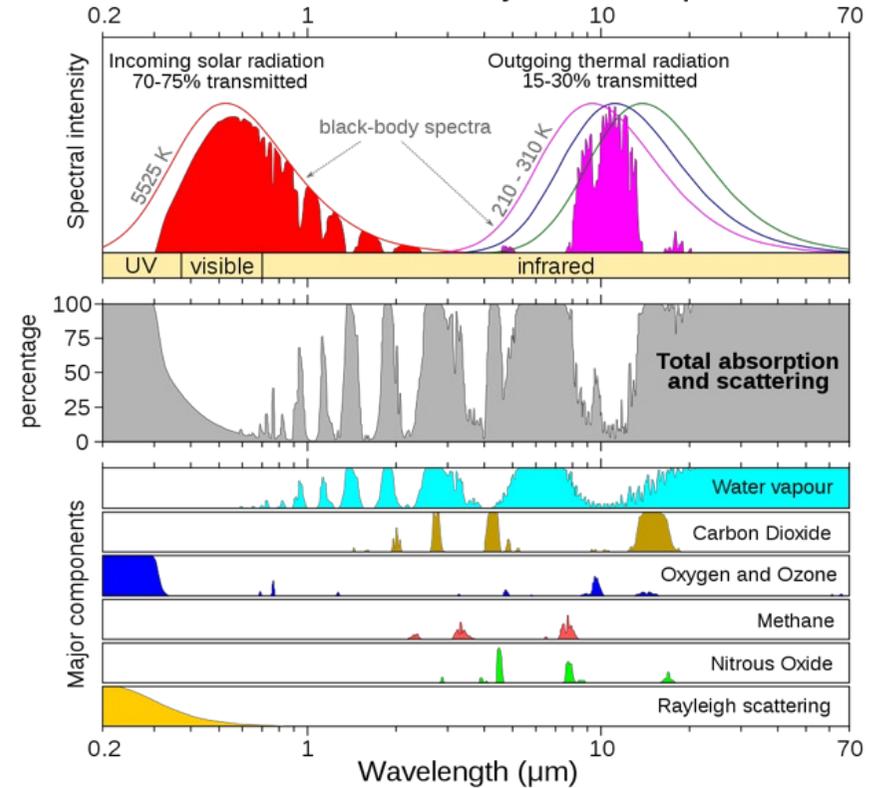
... are read out by ICs and SoC Module with image pre-processing

Emission and Absorption of Infrared Radiation

Radiation emitted from living human body (skin)



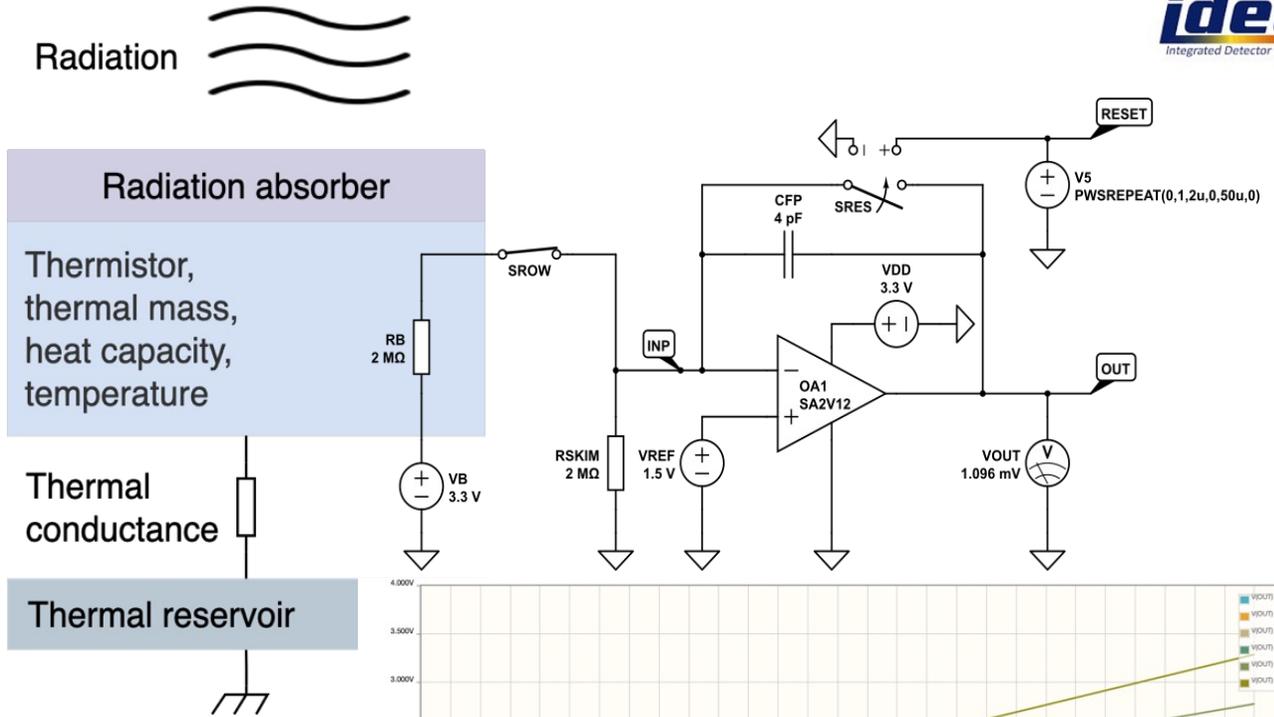
Radiation Transmitted by the Atmosphere



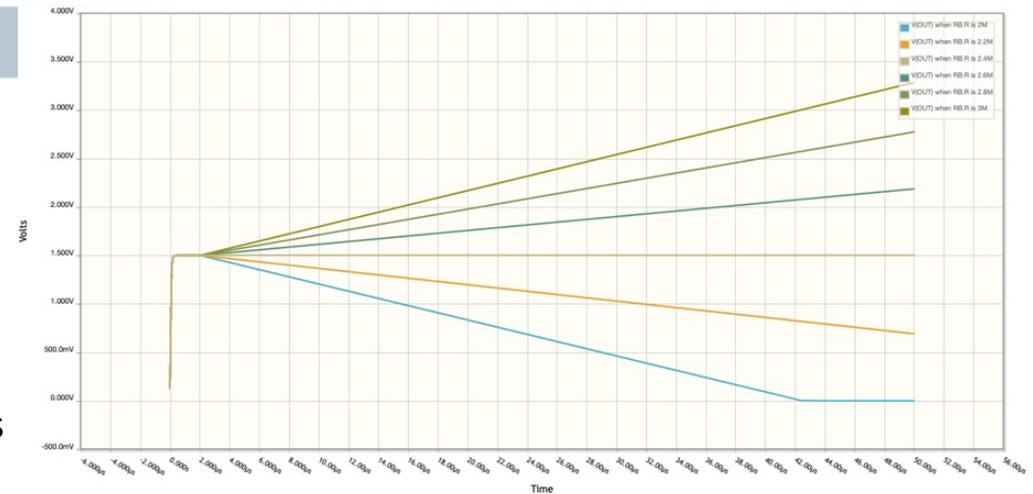
Objects emit radiation at Temperature and Emissivity

Water Vapor and Gases absorb Radiation

Principle of Microbolometer Electronic Readout

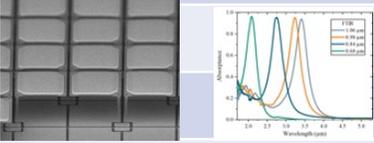
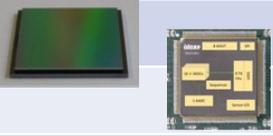
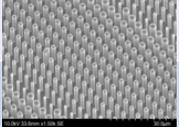
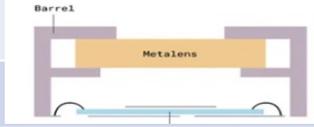


$$R_B = \frac{V_B - V_{REF}}{\frac{V_{REF}}{R_{SKIM}} + \frac{[V_{OUT}(t_2) - V_{OUT}(t_1)] * C_{FP}}{t_2 - t_1}}$$



Principle in www.circuitlab.com
Detailed design in CMOS using www.cadence.com tools

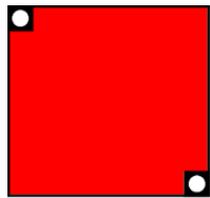
Overview of R&D Activities

R&D and Technology Innovation	What it Enables
<p>RD-1 - Microbolometer arrays</p>  <p>Vertical nanotubes Spectral absorbers</p>	<p>Room temperature operated FF, smaller pixels, higher resolution DOAS and T w/o ϵ</p> 
<p>RD-2 - CMOS Readout ICs</p>  <p>In-pixel memory (SA2V12 ROIC) Controller IC with ADC (NIRCA ASIC)</p>	<p>Low SWaP and cost Large temperature range Designed for analog MBA and FPA, i.e., MCT, InGaAs</p> 
<p>RD-3 - Diffractive infrared optics in silicon</p>  <p>Meta-optics binary etching Grayscale lithography</p>	<p>Low weight, flat lenses</p> 

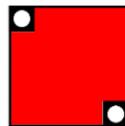
Uncooled Microbolometers

Nanotube technology*

- Scalable microbolometer technology up to 6 μ m pixel size
- Utilization of the largest possible area of the absorber layer



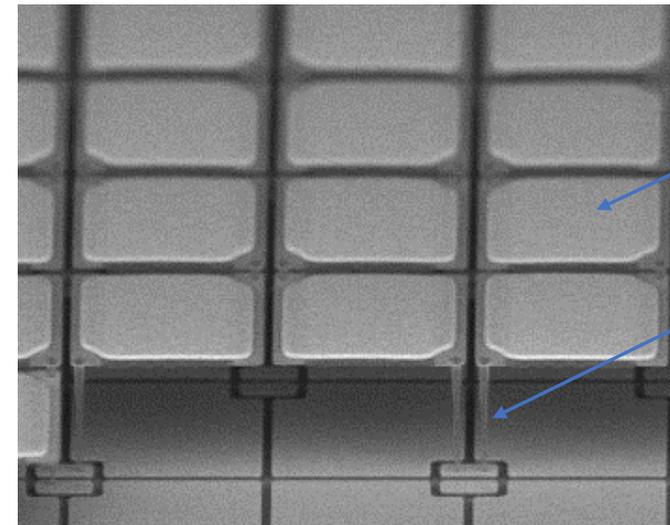
17 μ m



10 μ m



6 μ m



Sensor membrane

vertical nanotube

SEM-picture of the nanotube-microbolometers

*Michel, M., et al., Proc. SPIE 11537, Electro-Optical and Infrared Systems: Technology and Applications XVII, 1153704 (2020).

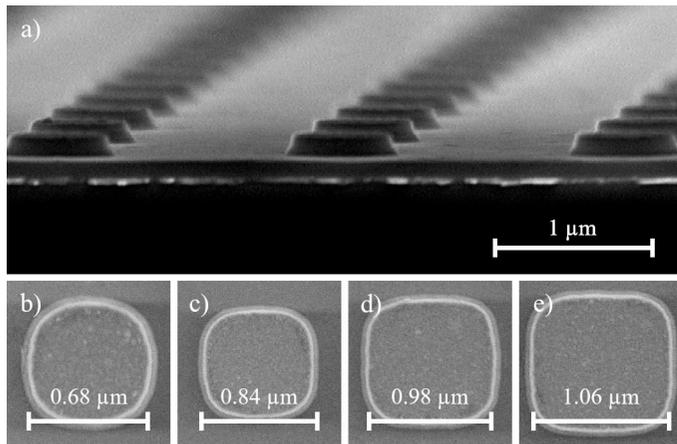
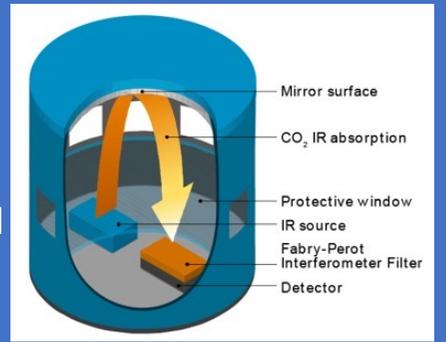
Plasmonic Metal-Insulator-Metal (MIM) Absorber

Selective absorption in MWIR

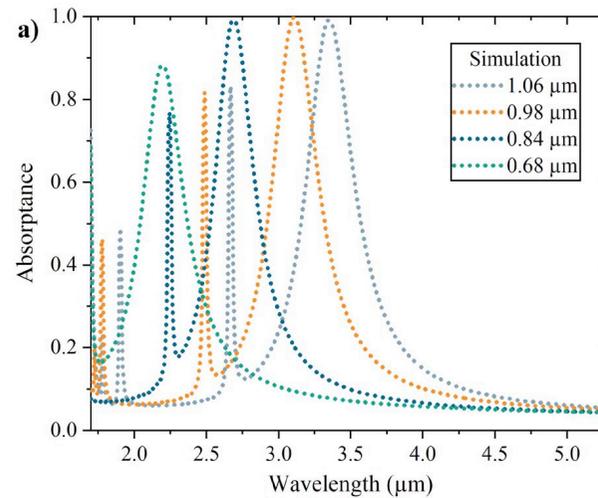
MIM test structure adaptable to Fraunhofer IMS's nanotube microbolometer for multispectral imaging**

Can MIM absorbers replace Fabry Perot in gas detectors?

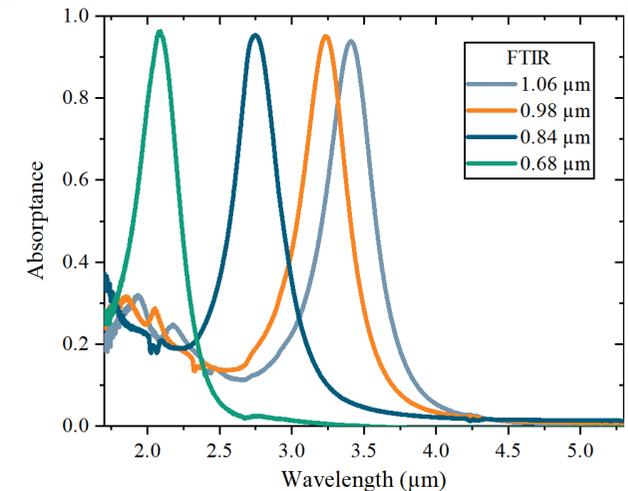
#DOAS – differential optical absorption spectroscopy



SEM-picture of fabricated MIM test structures



Simulation absorption spectra

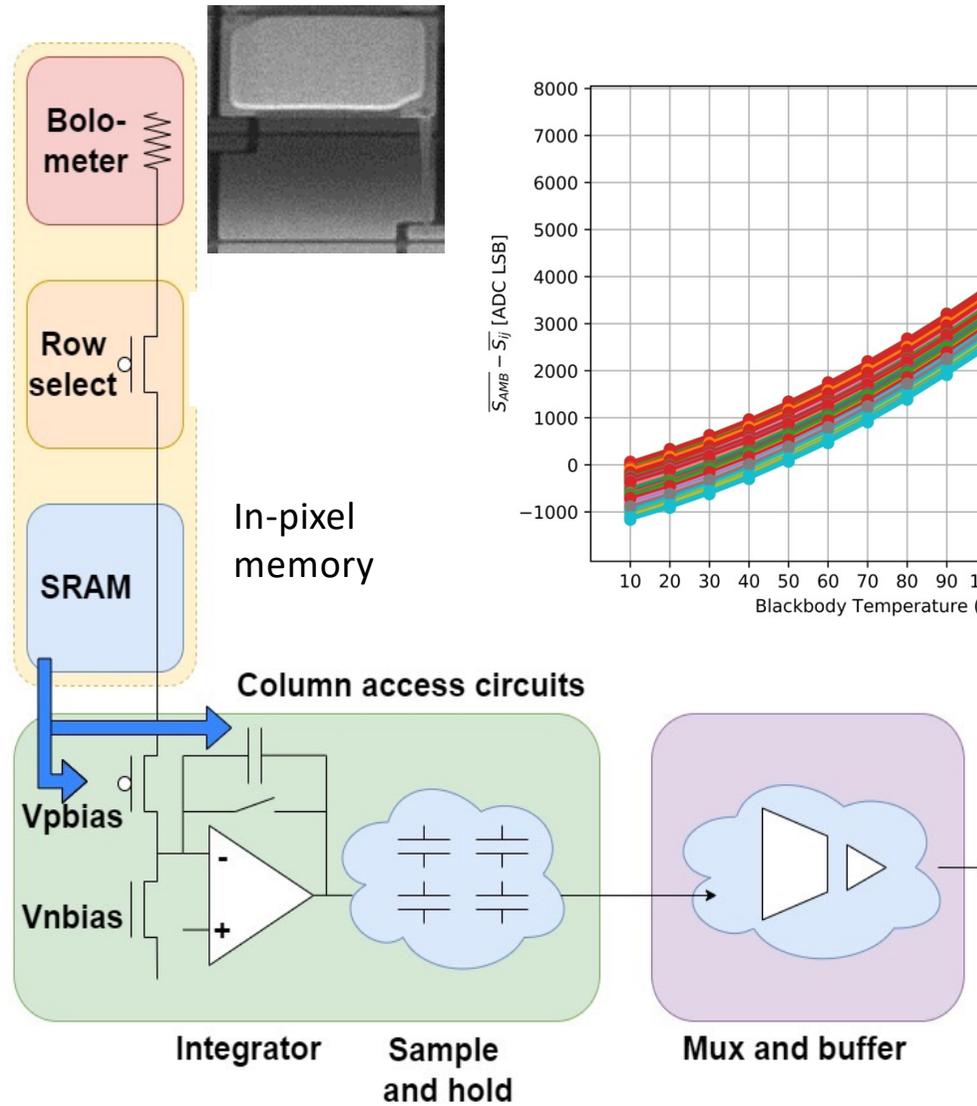


FTIR measurements of MIM test structures

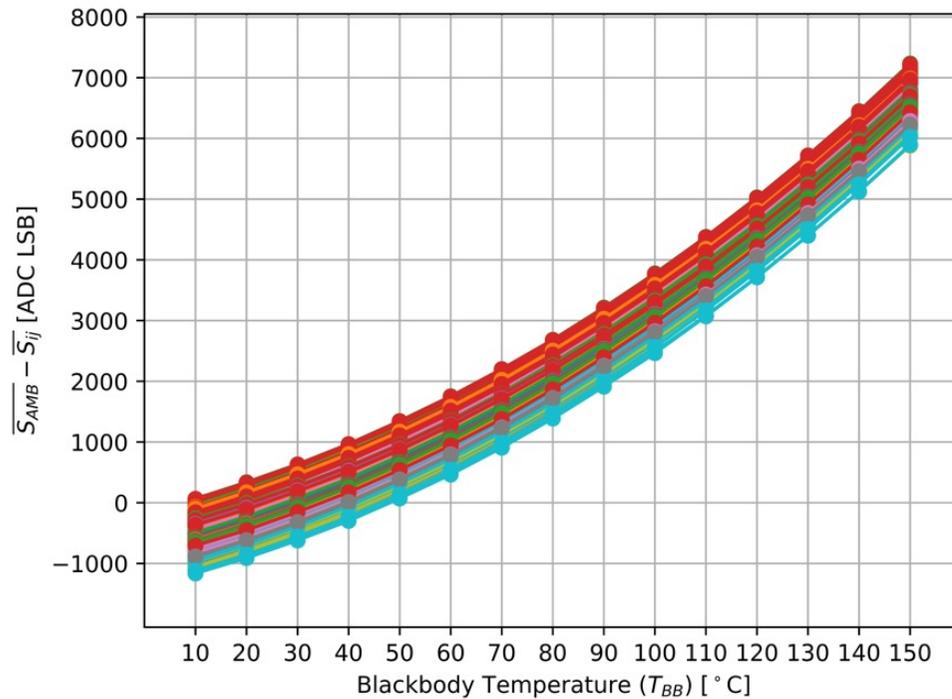
dirk.meier@ideas.no

Principle of Microbolometer Electronic Readout

R&D-2



Responsivity (Preliminary Measurement with 17um MBA)



SITF – signal transfer function

$$\bar{S}(i, j, T) \text{ [LSB]} \stackrel{\text{def}}{=} \frac{1}{200} \sum_{k=1}^{200} S_k(i, j, T) \text{ [LSB]}$$

Responsivity

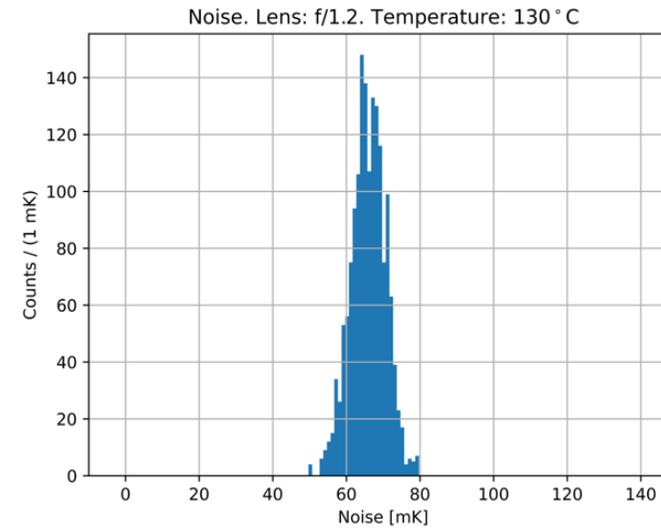
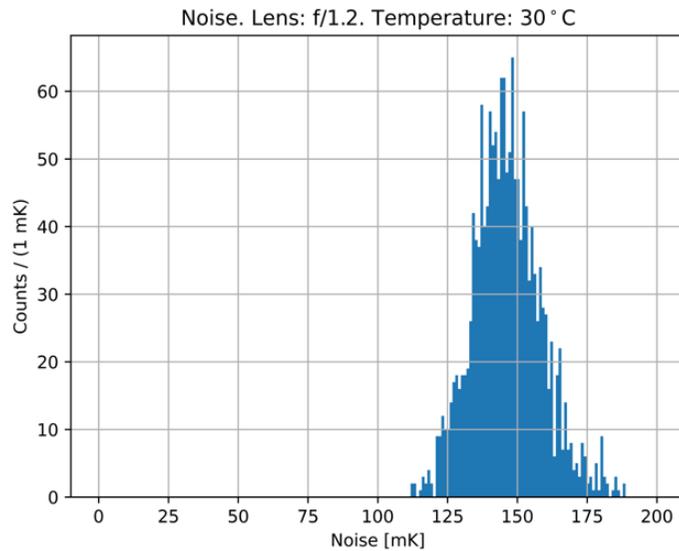
$$R(i, j, T) \left[\frac{\text{LSB}}{\text{K}} \right] \stackrel{\text{def}}{=} \frac{\partial P(i, j, T) \text{ [LSB]}}{\partial T \text{ [K]}}$$

With $P(i, j, T)$ is polynomial fit to $\bar{S}(i, j, T)$.

Temperature range 0°C up to 150 °C, higher temperatures are possible

NETD – Noise Equivalent Temperature Difference

(Preliminary measurement with 17um MBA)



NETD – Noise Equivalent Temperature Difference

$$\text{NETD}(i, j, T) [\text{K}] \stackrel{\text{def}}{=} \frac{\tilde{S}(i, j, T) [\text{LSB}]}{R(i, j, T) \left[\frac{\text{LSB}}{\text{K}} \right]}$$

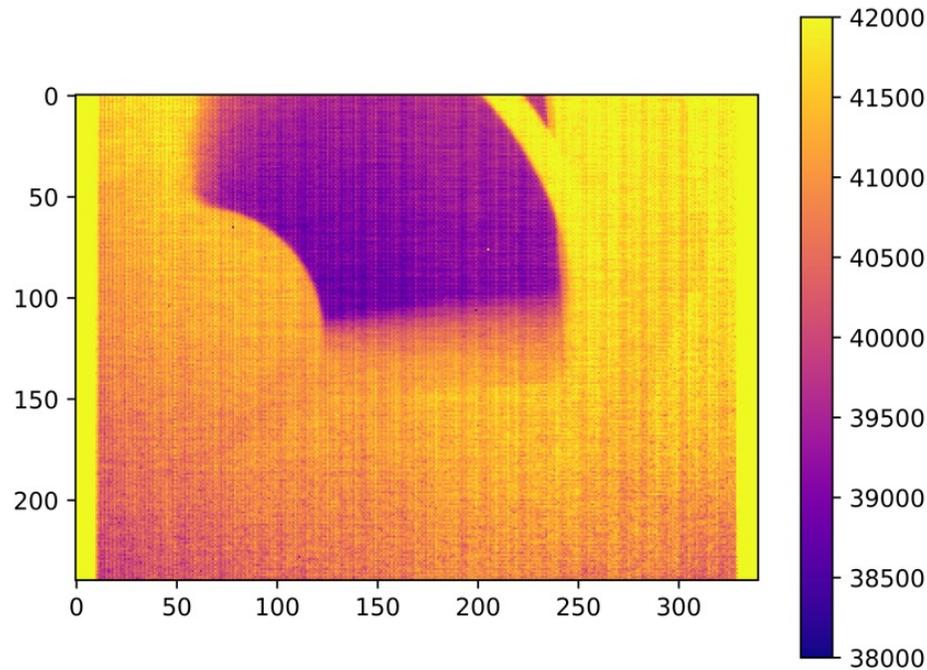
with

$$\tilde{S}(i, j, T) [\text{LSB}] \stackrel{\text{def}}{=} \sqrt{\frac{1}{200 - 1} \sum_{k=1}^{200} [S_k(i, j, T) [\text{LSB}] - \bar{S}(i, j, T) [\text{LSB}]]^2}$$

NETD at f/1.2 is 60mK to 170mK depending on temperature and other.

Blur from Thermal Time Constant

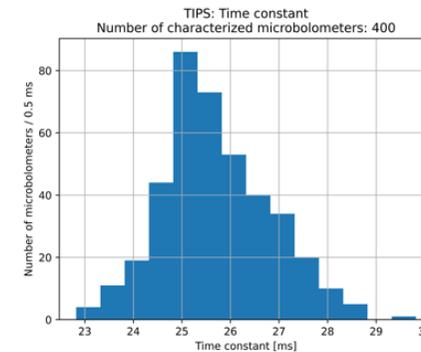
(Preliminary with 17um MBA)



Thermal time constant

$$\tau_{th} \stackrel{\text{def}}{=} \frac{C_{th} \left[\frac{J}{K} \right]}{G \left[\frac{W}{K} \right]}$$

Heat capacity C_{th} and thermal conductance $G \left[\frac{W}{K} \right]$

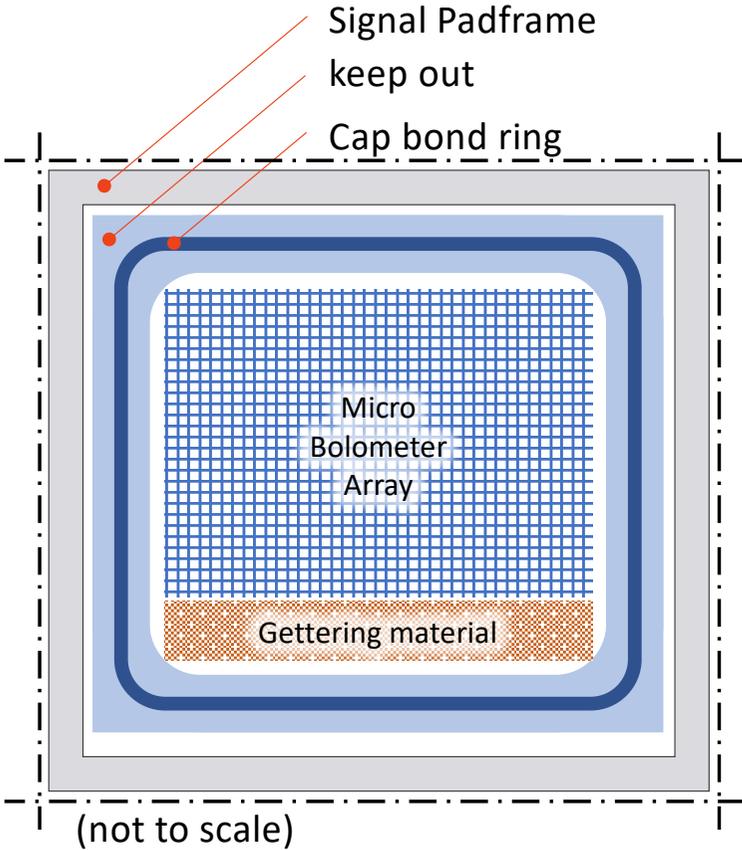
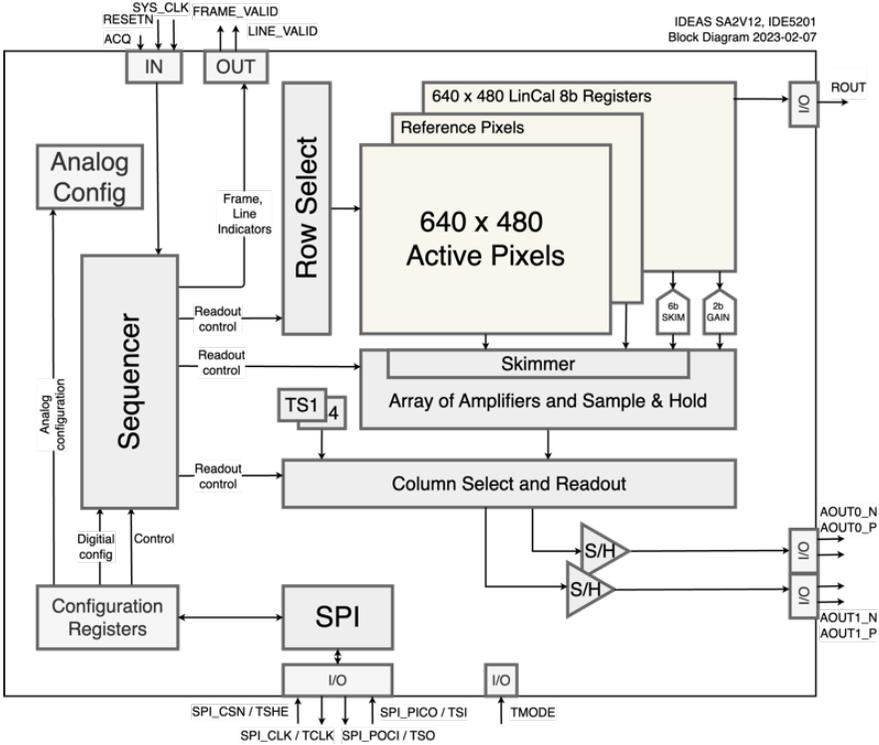


Preliminary: Thermal time constant of about 26ms (for these microbolometers)

R&D-2

SA2V12 ROIC for MBA

(2 Analog Out, VGA, 12µm Pixel Pitch)

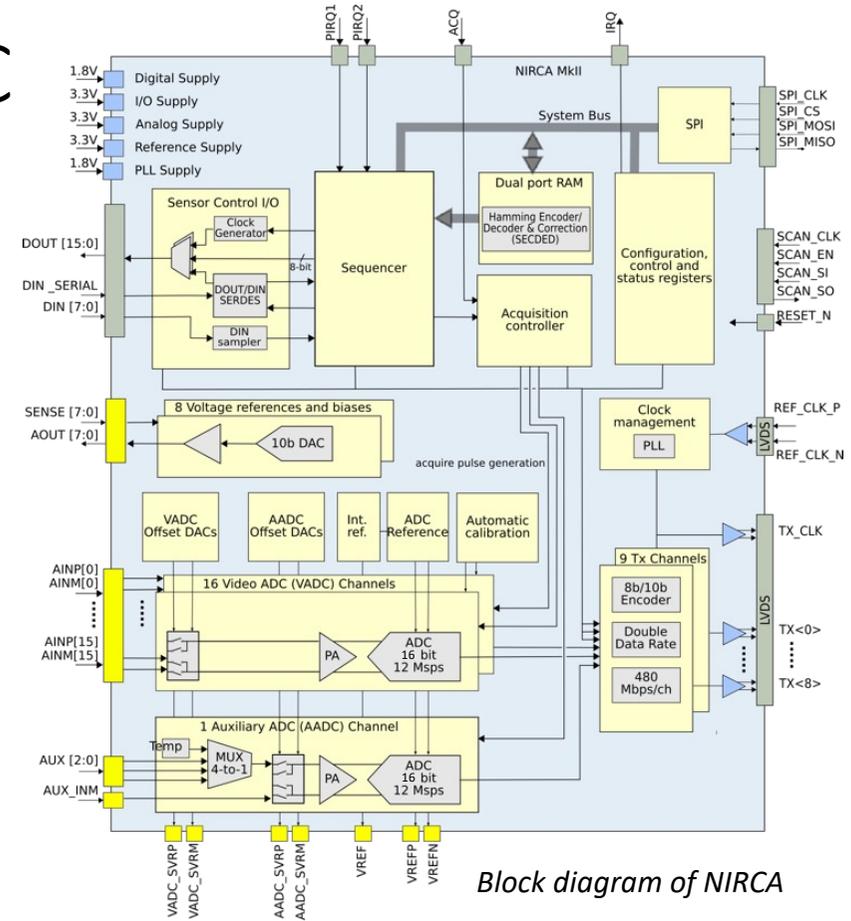
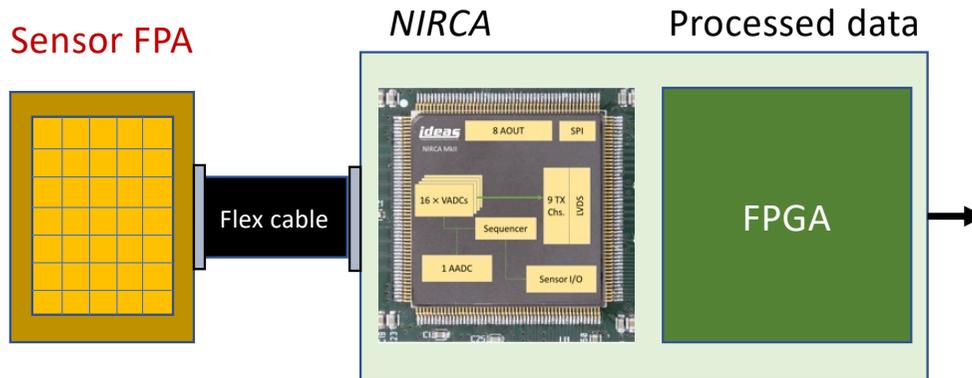


Block diagram of the ROIC, to be manufactured in CMOS. The Microbolometer array will be fabricated directly on the ROIC.

R&D-2

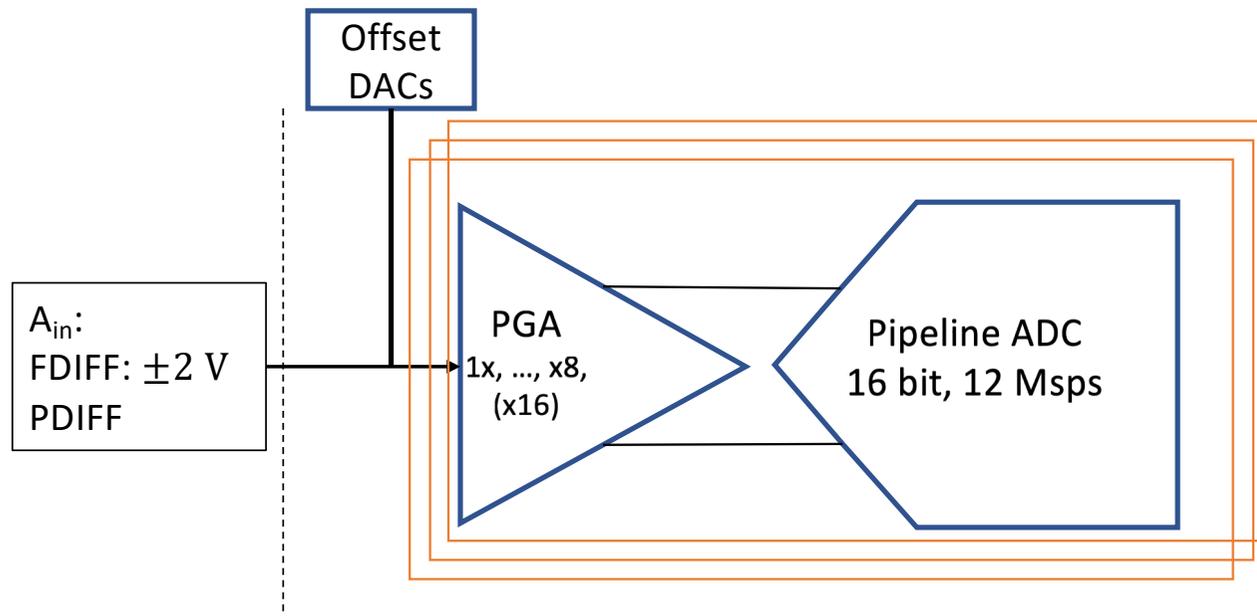
NIRCA – Near Infrared Readout Controller ASIC

- 17 ADCs (16-bit each) with sample rate of 12 MSPS to digitize analog data
- Output DACs to bias references
- I/O interface with sensor

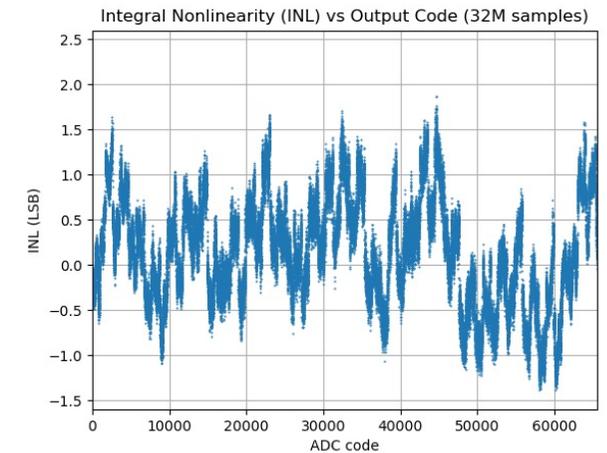
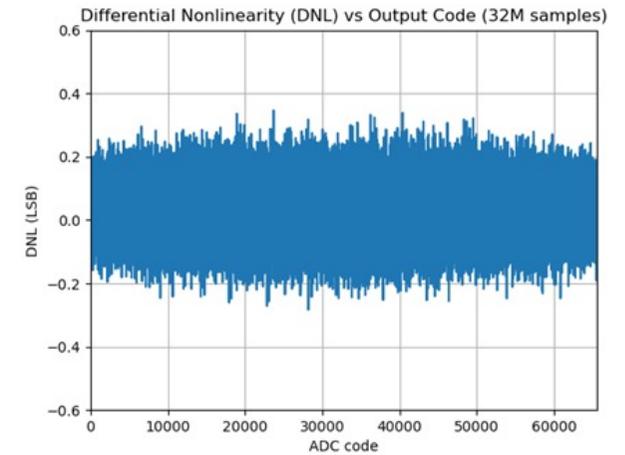


Block diagram of NIRCA

NIRCA A/D converters

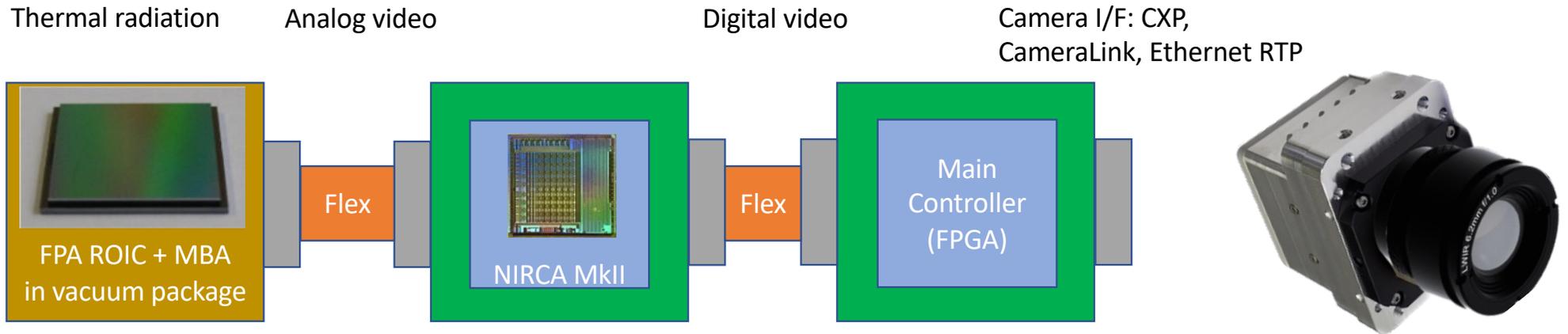


- 16 Video ADCs + 1 auxiliary ADC
- $C_{in} = 7 \text{ pF}$



R&D-2

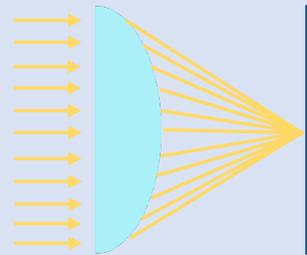
Thermal IR MBA + NIRCA + SoC Module



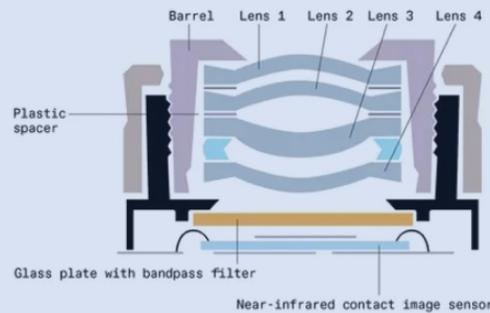
R&D-3

Optics for Thermal Infrared

Example Refractive Lens Assemblies



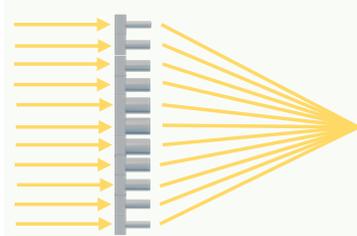
Conventional lenses



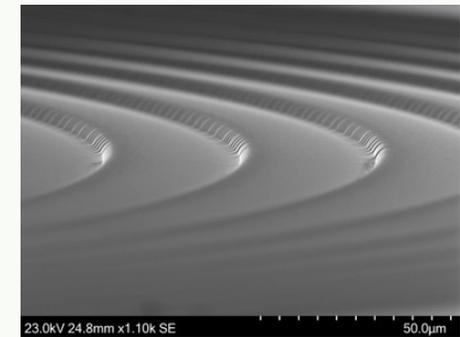
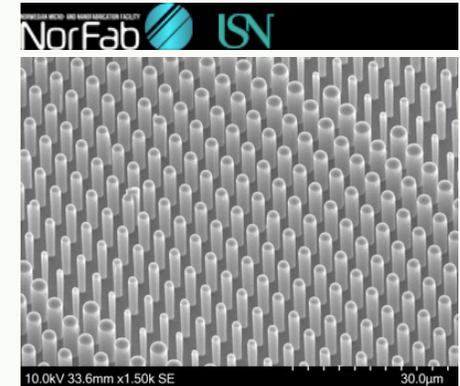
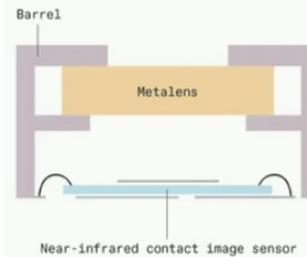
- Refractive optics with lens assembly from
1. Chalcogenide GASIR®
 2. Germanium
 3. Fresnel mold

A single metalens [right] can replace a stack of traditional lenses [left], simplifying manufacturing and dramatically reducing the size of a lens package. METALENZ

R&D with Metalens and Grayscale lithography

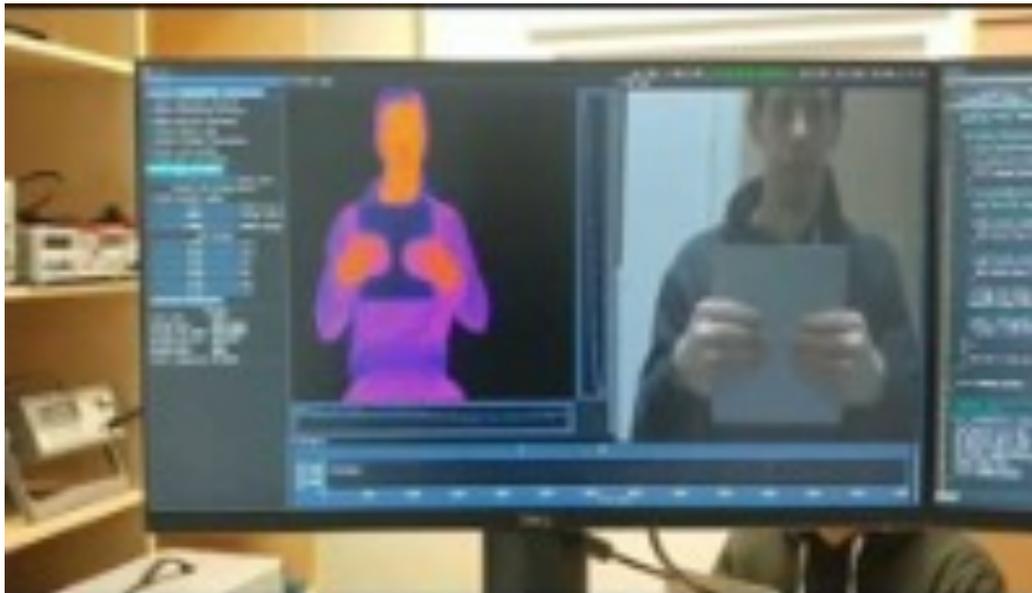


Metalenses



Design and fabrication at NorFab/USN [Bouchouri and Akram] in collaboration with IDEAS. Lens of f/2, Ø8mm, 10µm CWL monochrome, silicon pillars of 6.3µm height and 5µm pitch.

Demonstration of a Thermal Infrared Camera



Rihards Novickis, Edgars Lielamurs et al. at EDI, <https://youtu.be/aXIDwRos-gl>

click



Features

Sensor technology	Silicon MBA, 17 μ m QVGA, CSP
Data Interface	Ethernet
Lens	Umicore GASIR [®] IR, 7.5mm, f/1.2
Spectral range	Mid- and long wave infrared
Temperature FOV	0°C to +400°C
NETD at f/1.0	47mK 120°C, 94mK at 30°C
Thermal time constant	25.7ms
Frame rate	30fps
Data acquisition system	Xilinx ZCU102 MPSoC
Operating temperature	-20°C min, +60°C max



Description

The TC-N1 camera system demonstrates video-rate thermal infrared (IR) imaging at 30fps with a focal plane array (FPA) based on silicon microbolometers (MBA). The IRFPA has 320 × 240 active pixels at 17- μ m pixel pitch and has been fabricated in a standard CMOS process certified for automotive applications followed by MEMS process to realize microbolometers and a chip-scale vacuum-package (CSP). The camera is sensitive to thermal radiation (heat) over several hundreds of degrees Celsius with average noise of 94mK at +30°C and 47mK at +120°C (NETD, normalized to f/1.0). Details of the design must be customized and optimized for the intended applications.



Applications

The TC-N1 is a thermal infrared camera for the purpose of technology evaluation and demonstration. The technology is intended for camera manufacturers and system integrators. Possible applications are in thermography, security, and safety, automotive, firefighting and others.

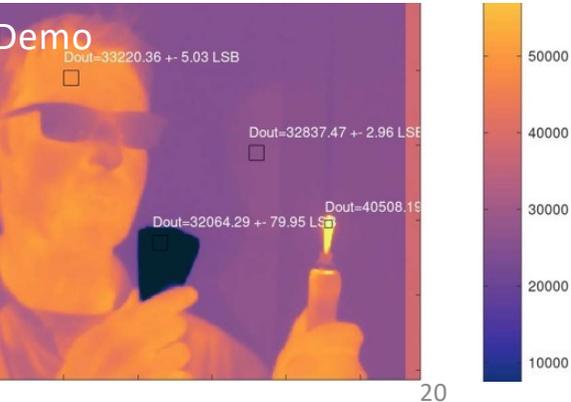
Camera Demonstrator Tests

click



https://youtu.be/ir_Ntlkv5is

IDEAS Ambition is to supply Thermal Infrared Camera Modules to OEMs



High-performance thermal infrared camera modules

- MBA – Microbolometer Array, **uncooled and room-temperature operated**
- TSense – Temperature Sensing and Radiometric
- PxPy – Pixel in X and Y, VGA, such as SA2V12 and **higher resolution**
- FOM – Figure of Merit, low NETD and short time constant

Enable OEMs to offer new solutions in thermography

- MIM – Metal insulator metal, multi-spectral bands, <https://doi.org/10.1117/12.2638111>
- SWaP – Size, weight, and power are low, e.g., metalens, Bouchouri et al. ELOS2022

Capability for customizations and increase sovereignty

- Non-US ITAR, made-in-Europe, European sovereignty

About IDEAS

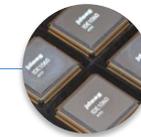
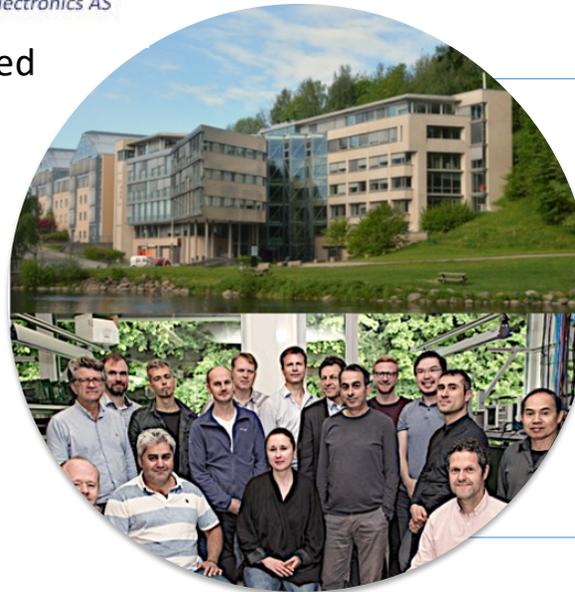
IDEAS is a Norwegian company (SME), located in Oslo, founded in 1992.

IDEAS designs and supplies

- Electronic **integrated circuits**,
- **Sensor components, systems, modules.**

Team of about 28 employees, with background in electronics, software, radiation physics and material science.

www.ideas.no



IC
Designer/Supplier



Radiation Detectors

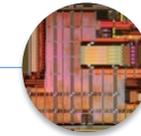


Image Sensors



Special
Apps/Ops/Env

For 30 year, the company has been developing electro-optical systems for radiation detection and imaging.

We focus on **performance-defining and proprietary ROIC/ASICs and sensor components (semiconductors + MEMS).**

Our customers are in **scientific and emerging imaging technologies** with disruptive market potential.

Acknowledgements

Project	Program
NIRCA	ESA contracts + IDEAS, ~10 years
MINC	Eurostars Eureka Grant + IDEAS, 2016-2018, 3years
SPEKTIR	Eurostars Eureka Grant + IDEAS, 2020-2024, 4years
APPLAUSE UC2	ECSEL JU, H2020/NFR Grant + IDEAS, 2019-2022, 42months
MANTIS	IPN, NFR Grant + IDEAS, 3years
MANTIS Vision	Euripides Penta, IDEAS, 3years
AGRARSENSE	KDT JU, H2020/NFR Grant + IDEAS, 2023-2025, 3 years
CENSSS	SFI, NFR Grant + IDEAS

